Supporting Information

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DNA-Based Fabrication of Density-Controlled Vertically Aligned ZnO Nanorod Arrays and Its SERS applications

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Figure S1 (a) Tapping mode AFM image of DNA networks on ITO surface after six times of Zn\(^{2+}\) wetting treatment, (b) corresponding height distribution histogram of AFM image of (a).

Figure S2 Tapping mode AFM images of DNA structures on ITO surface with various DNA concentration: (a) 5 and (c) 20 ng/\(\mu\)L, (b) and (d) SEM images of correspondingly obtained ZnO NRs arrays.
Figure S3 (a) SEM image and (b) UV-vis absorption spectrum of ZnO NRs grown on glass.

Figure S4 UV-vis absorption and transmission spectra of pure ITO slide.